# A Fizeau interferometer system for characterising and optimising large synchrotron mirrors

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# Summary

A Fizeau interferometer system, using a MiniFiz150, has been developed to characterise and optimise the figure error of large synchrotron mirror assemblies using single-pass, double-pass, or stitching modes [1, 2]

### **System Parameters**

- Designed to measure mirrors <0.15m in single-pass mode using  $\lambda$ /100 PV reference flat  $\bullet$
- Mirrors from 0.15m 2m long are characterised in double-pass mode using  $\lambda/100$  and  $\lambda/20$ •
- Accommodates upwards, downwards, and sideways facing mirrors in double-pass mode  $\bullet$
- Load capacity >100kg enables entire, mounted mirror assemblies to be investigated  $\bullet$

**System Schematic and Degrees of Freedom Mirror geometry**  $\theta$  = Grazing Angle  $\lambda$ /100 reference flat Upwards facing  $\gamma_2 = 0$ ,  $\gamma_1 = -\gamma_3 = -\theta$   $\alpha_1 = \alpha_2 = 0$ **Downwards facing**  $\gamma_2 = 0, -\gamma_1 = \theta = \gamma_3$   $\alpha_1 = \alpha_2 = 0$ Sideways facing  $\gamma_1 = \gamma_2 = \gamma_3 = 0$   $\alpha_1 = \theta, \alpha_2 = 2\theta$ **Mirror under test** 

**MiniFiz interferometer** 

- Optimised system repeatability of ~2nm rms is sufficient for most synchrotron optics •

## Advantages

- Quick and simple to switch between operating modes
- 2-D figure data captured for entire optical surface  $\bullet$
- Short acquisition times (<1min) enable dynamic surface changes to be investigated
- Complementary to slope-measuring profilers, such as • the Diamond-NOM [3]









Mounted mirror (I13) tested using double-pass mode, sideways configuration

VFM bimorph mirror (I04) tested using double-pass mode, upwards configuration

# Using the MiniFiz to optimise the figure error of mounted mirror systems



#### **Effect of Mirror mounting**

Optimum clamping and cooling conditions can be determined prior to beamline installation

- Unmounted mirror of high quality and flatness (-429km)
- Mounted & unclamped mirror very similar to unmounted.
- Clamped mirror becomes





#### For optimum quality, data acquired when:

- Cleanroom fans turned off
- Interferometer cavity is thermally stable (10min "time window")
- Optical bench vibration isolated

Laser vibration sensor used to



- distorted (-52km) and worse figure error
- After iteratively changing the clamping and cooling water temperature, mirror is optimised

After clamping After temperature optimisation : T = 20.5C

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# References

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